Feedback

Joel Voldman* Massachusetts Institute of Technology *(with thanks to SDS)

Outline

- > Motivation for using feedback
- > The uses of (linear) feedback
- > Feedback on Nonlinear Systems
 - Quasi-static systems
 - Oscillators

Why use feedback?

- > For actuators, how do you know when you have actuated?
 - You can calibrate/calculate/etc., but what about drifts?
- > Adding a sensor can tell you where you are
- Combining the sensor + actuator with feedback can keep you where you are

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An optical attenuator that uses

- MEMS actuator
- Senses optical output
- Uses feedback to control attenuation

Why use feedback?

- > For sensors, feedback can be used to enhance sensor response
 - E.g., keep sensitivity constant
- Must add an actuator to do this

An accelerometer that uses

- MEMS tunneling sensor
- Electrostatic actuation
- Uses *feedback* to control tunneling current (and thus gap)

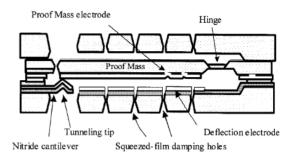


Figure 1 on p. 426 in: Liu, C.-H., and T. W. Kenny. "A High-precision, Wide-bandwidth, Micromachined Tunneling Accelerometer." *Journal of Microelectromechanical Systems* 10, no. 3 (September 2001): 425-433. © 2001 IEEE.

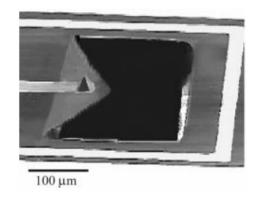


Figure 3a) on p. 426 in: Liu, C.-H., and T. W. Kenny. "A High-precision, Wide-bandwidth, Micromachined Tunneling Accelerometer." *Journal of Microelectromechanical Systems* 10, no. 3 (September 2001): 425-433. © 2001 IEEE.

Feedback in MEMS

- Since MEMS is often concerned with making sensors for measurements or actuators to do something, feedback is integral to the subject
- Here we will examine some of the basic uses of feedback
 - Limit sensitivity to variations
 - Speed up system
 - Stabilize unstable systems
- > At the end, we will look at feedback in nonlinear systems, which is useful for making oscillators

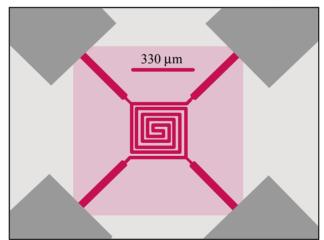
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Example: A MEMS hotplate

Wet SiO2

- > Used for gas sensor
- Heat up active material, which reacts with gas and changes resistance
- > Thermal MEMS is used because
 - Low power
 - Fast
 - Arrayable



TiN/Ti. 200/10 nm Membrane low-stress SiN_x, 2x 500 nm Si wafer 1 mm 0.33 mm Image by MIT OpenCourseWare. Image removed due to copyright restrictions.

Heater coil, bond pad

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The Canonical Feedback System

In controls, terminology refers to the plant, the controller, the state sensor, and the comparison point

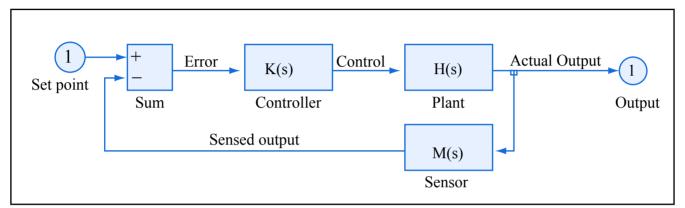


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Adapted from Figure 15.1 in Senturia, Stephen D. Microsystem Design. Boston, MA: Kluwer Academic Publishers, 2001, p. 397. ISBN: 9780792372462.

Example: micro hotplate

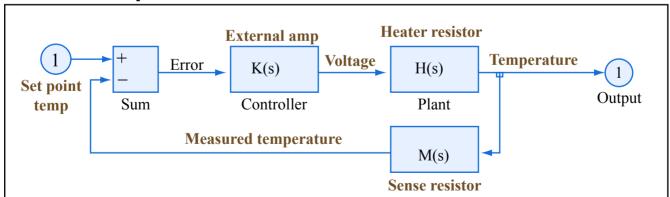


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Adding Noise and Disturbances

- > Noise corrupts the sensor output
- > Disturbances modify the control input to the plant
- In some cases, what we want to measure is the disturbance (a feedback-controlled accelerometer)

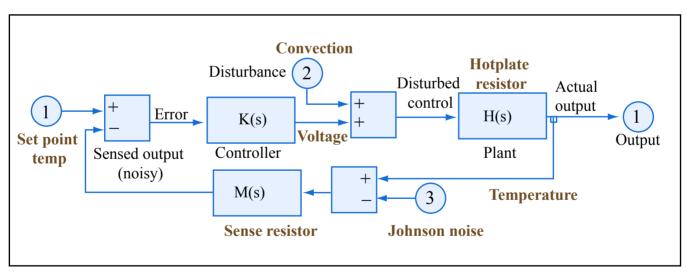
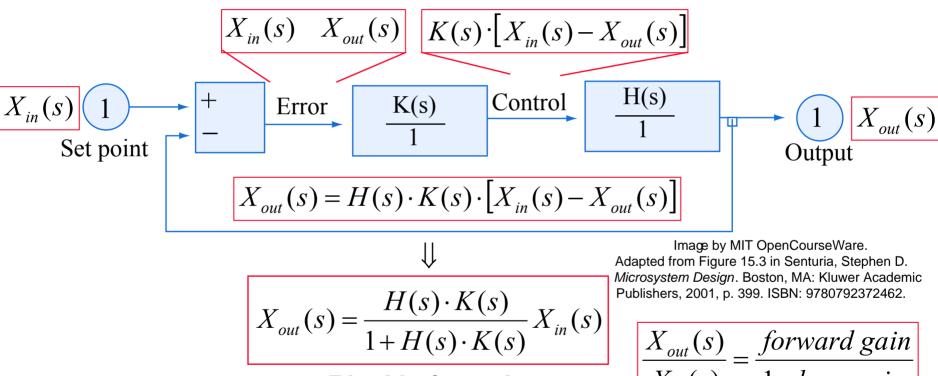


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Linear Feedback: Black's Formula

- > For a LTI system, we can use Laplace transforms to create an algebraic closed-loop transfer function
 - Assume sensor has (perfect) unity transfer function



Black's formula

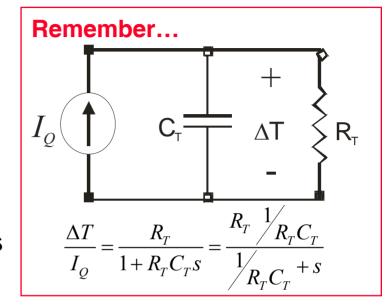
$$\frac{X_{out}(s)}{X_{in}(s)} = \frac{forward\ gain}{1 - loop\ gain}$$

Open-Loop Operation

- > Control hot plate via calibration
 - Assume hotplate has 1st-order response with s₀~400 rad/s (f₀~65 Hz)
 - Assume controller has no dynamics

$$H(s) = \frac{A_0 s_0}{s + s_0}$$
 $K(s) = K_0$

- Works great if there are no disturbances or drifts in system
- > Any deviations cause steady-state error



$$T_{\text{set}} \xrightarrow{T}_{\text{cal}} + K(s) \xrightarrow{H(s)} + T_{\text{hotplate}}$$

$$T_{hotplate} = T_{room} + H(s)K(s)(T_{set} - T_{cal})$$

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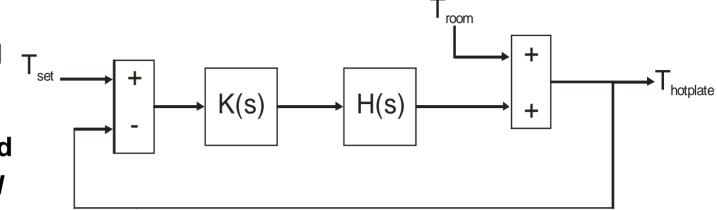
Open-Loop Operation

> Response is sensitive to variations in controller, plant, and disturbances

$$T_{room} = 23 \, {}^{\circ}\text{C}, K_{0} = 1.2$$
 $T_{room} = 25 \, {}^{\circ}\text{C}, K_{0} = 1$
 $T_{room} = 23 \, {}^{\circ}\text{C}, K_{0} = 1$

Feedback use #1: limit sensitivity to variations

- Add in term proportional to error
- > This is called proportional control



$$\begin{split} T_{hotplate} &= \frac{HK}{1 + HK} T_{set} + \frac{1}{1 + HK} T_{room} \\ &= \frac{\frac{A_0 S_0}{s + s_0} \cdot K_0}{1 + \frac{A_0 S_0}{s + s_0} \cdot K_0} T_{set} + \frac{1}{1 + \frac{A_0 S_0}{s + s_0} \cdot K_0} T_{room} \end{split}$$

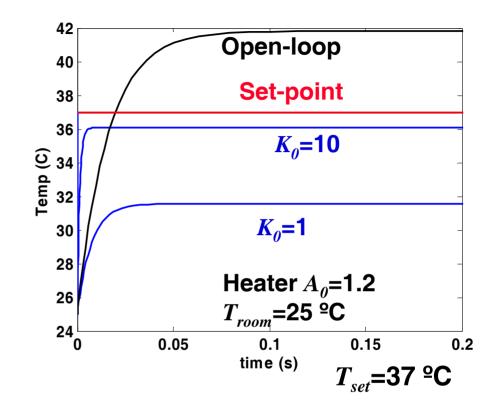
Closed-loop TF

$$T_{hotplate} = \frac{A_0 K_0 S_0}{s + s_0 \left(1 + A_0 K_0\right)} T_{set} + \frac{s + s_0}{s + s_0 \left(1 + A_0 K_0\right)} T_{room}$$

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Close the loop

- > Error → 0 as K₀ increases, despite
 - Variations in device (A₀)
 - Variations in plant (K₀)
 - Disturbances (T_{room})
- > In limit of large K₀, system responds "perfectly"
 - Though DC error never goes exactly to zero



Steady-state (DC) Error

$$\left| \mathcal{E}(s) \right|_{s=0} = T_{set} - T_{hotplate} = \frac{1}{1 + A_0 K_0} T_{set} - \frac{1}{1 + A_0 K_0} T_{room}$$

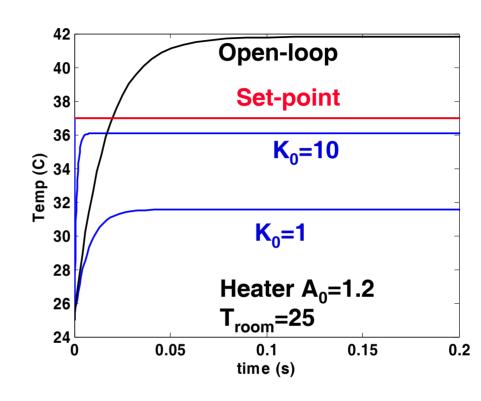
Feedback use #2: increase system bandwidth

- > Settling time goes down
- > Bandwidth goes up

$$H(s) = \frac{A_0 s_0}{s + s_0}$$

$$\frac{T_{hotplate}}{T_{set}} = H_{cl}(s) \approx \frac{A_0 K_0 s_0}{s + s_0 (1 + A_0 K_0)}$$

$$s_0 \to s_0 (1 + A_0 K_0)$$



Controlling a 2nd-order system

- > Vibration sensor
 - Really just an z-axis accelerometer
- > Use feedback to keep gap constant
- In this case, control signal measures vibration
- > Mechanical "plant" is a SMD

$$H(s) = \frac{X_{out}(s)}{F(s)} = \left(\frac{1}{k}\right) \frac{1}{\hat{s}^2 + \frac{1}{Q}\hat{s} + 1}$$

where:
$$\hat{s} = \sqrt[S]{\omega_0}$$
, $\omega_0 = \sqrt{\frac{k}{m}}$, $Q = \frac{m\omega_0}{b}$

- •Set Q=1/2 (critically damped)
- •Set *k*=1 for convenience

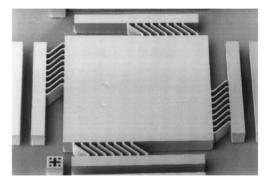


Figure 4 on p. 435 in: Bernste in, J., R. Miller, W. Kelley, and P. Ward. "Low-noise MEMS Vibration Sensor for Geophysical Applications." *Journal of Microelectromechanical Systems* 8, no. 4 (December 1999): 433-438. © 1999 IEEE.

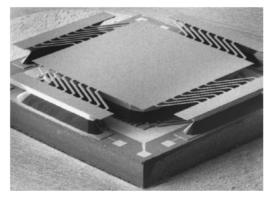


Figure 6 on p. 435 in: Bernste in, J., R. Miller, W. Kelley, and P. Ward. "Low-noise MEMS Vibration Sensor for Geophysical Applications." *Journal of Microelectromechanical Systems* 8, no. 4 (December 1999): 433-438. © 1999 IEEE.

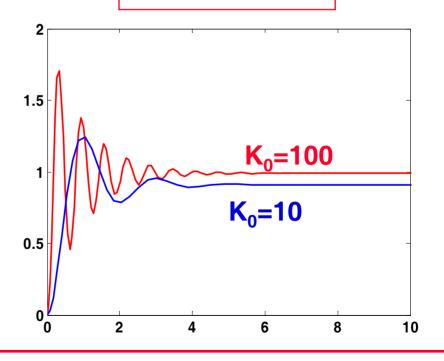
Proportional control of 2nd-order system

- > Use ideal controller $K(s)=K_0$
- > This gives us two overall poles:
 - Two from SMD H(s)
 - None from controller *K*(*s*)
- Some results are same as 1storder system
 - Decreasing DC error as K₀ increases
 - System speeds up
- Some differences:
 - Q of closed-loop response increases with increasing DC gain
- This means that our critically damped system is now underdamped
 - This can be bad or fatal for our system

$$\frac{X_{out}(s)}{X_{in}(s)} = \frac{H(s)K(s)}{1 + H(s)K(s)} = \frac{K_0}{\hat{s}^2 + \frac{1}{Q}\hat{s} + (K_0 + 1)}$$

$$\omega_{0,cl} = \sqrt{K_0 + 1}$$

$$Q_{cl} = Q\sqrt{K_0 + 1}$$



Control of complex systems

- > Dynamics of closed-loop system are determined by H(s)K(s)
- > Thus, behavior seen with 2nd-order SMD system will also occur with 1st-order thermal system coupled to 1st-order controller
- > What happens when we add an additional pole?

Single-Pole Controller (Real amp)

- Take SMD and control with 1st-order controller
- The system now has three poles
- When going to large K₀, the system goes unstable
 - This happens if one of the roots has real positive part
- > Routh test can be used to find maximum gain

$$K(s) = \frac{K_0}{1 + \hat{s} \, \hat{\tau}} \qquad \hat{\tau} = \omega_0 \tau$$

$$\downarrow \qquad \qquad \text{controller}$$

$$\text{time constant}$$

$$\frac{X_{out}(s)}{X_{in}(s)} = \frac{K_0}{\hat{\tau}\hat{s}^3 + (1 + 2\hat{\tau})\hat{s}^2 + (2 + \hat{\tau})\hat{s} + K_0 + 1}$$

Routh test for third - order system:

$$a_3s^3 + a_2s^2 + a_1s + a_0$$

All coefficients (a_n) must have same sign

AND
$$a_2 a_1 > a_0 a_3$$
 $\downarrow \downarrow$

$$K_0 < \frac{1}{Q} \left(\frac{1}{Q} + \hat{\tau} + \frac{1}{\hat{\tau}} \right)$$

2nd-order vs. 3rd-order systems

Stable system at all loop gains

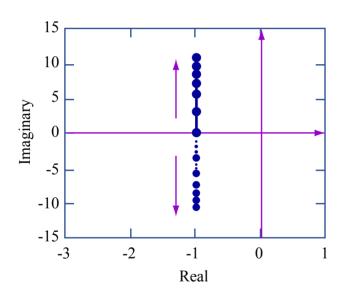


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Adapted from Figure 15.5 in: Senturia, Stephen D. Microsystem Design.

Boston, MA: Kluwer Academic Publishers, 2001, p. 402. ISBN: 9780792372462.

> Unstable system at sufficiently high loop gain

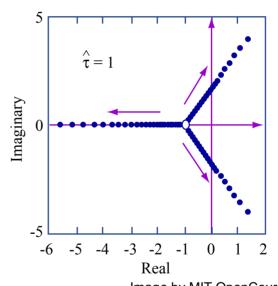


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Effect of controller bandwidth

Controller bandwidth < Plant bandwidth causes controller to dominate overall response

 $\tau = 1$

Q=1/2 ω_0 =1 K_0 =6 τ =100

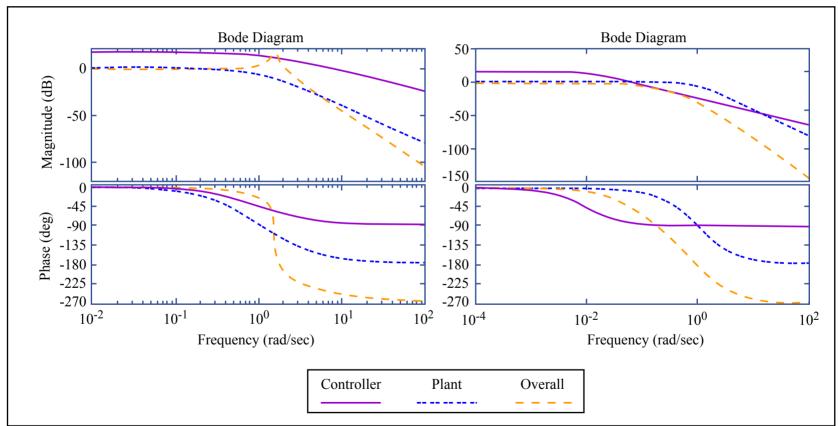


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Effect of controller bandwidth

Controller bandwidth > Plant bandwidth causes plant to dominate overall response

 $\tau = 1$

Q=1/2 $\omega_0=1$ $K_0=6$

 τ =0.01

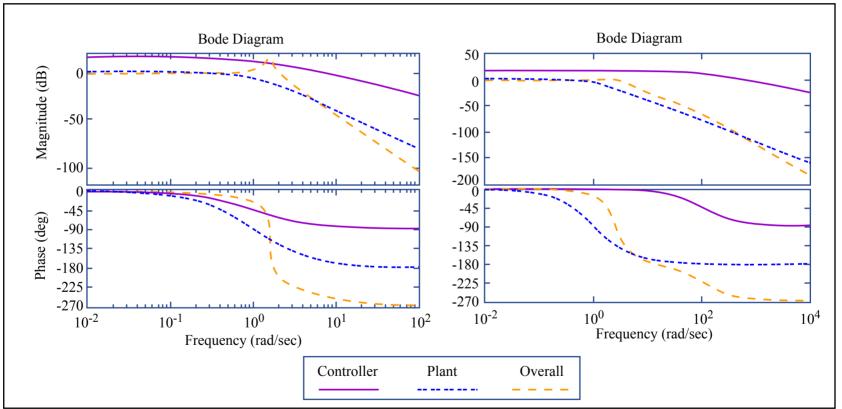


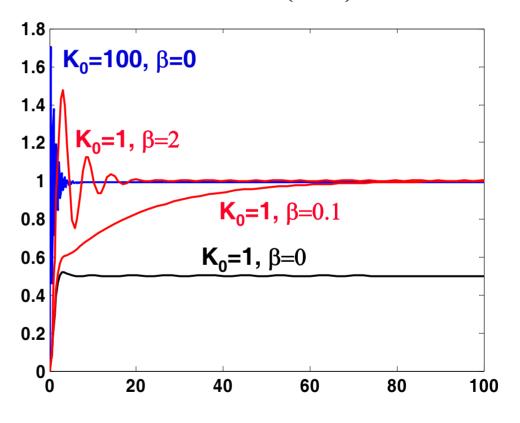
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PI control

- > Add pole at s=0
- > This gives $K(0) \rightarrow \infty$
 - And thus no DC error
- > Benefits
 - As long as β≠0, will get perfect DC tracking, but it may take awhile
 - Completely insensitive to changes in plant at DC
- > Drawbacks
 - Additional pole means possibility of ringing and instability

Proportional - Integral (PI) Control:

$$K(s) = K_0 \left(1 + \frac{\beta}{s} \right)$$



PID control

- > Final generic term is to add in differential feedback
 - Anticipate future
- "Tame" ringing and instability due to integral and proportional control
- Methods exist to tune PID controllers

Proportional - Integral - Differential (PID) Control:

$$K(s) = K_0 \left(1 + \frac{\beta}{s} + \gamma s \right)$$

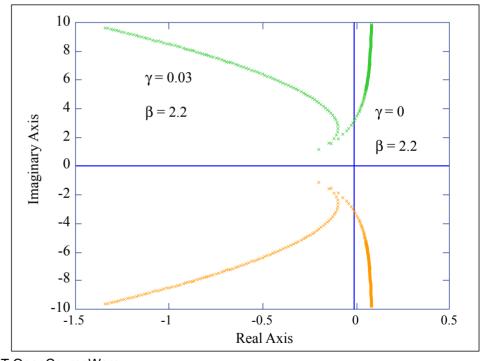


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Stabilization of unstable systems

Piyabongkarn (2005), IEEE Trans. Control Systems Tech.

- > Use of feedback #3: Stabilize an unstable system
- Stabilize electrostatic actuator beyond pull-in
- Most approaches use feedback to approximate charge control

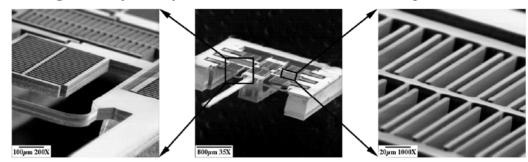


Figure 2 on p. 139 in: Piyabongkarn, D., Y. Sun, R. Rajamani, A. Sezen, and B. J. Nelson. "Travel Range Extension of a MEMS Electrostatic Microactuator." *IEEE Transactions on Control Systems Technology* 13, no. 1 (January 2005): 138-145 © 2005 IEEE.

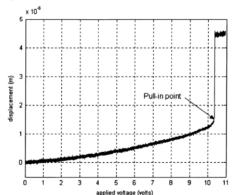


Figure 6 on p. 140 in: Piyabongkarn, D., Y. Sun, R. Rajamani, A. Sezen, and B. J. Nelson. "Travel Range Extension of a MEMS Electrostatic Microactuator." *IEEE Transactions on Control Systems Technology* 13, no. 1 (January 2005): 138-145. © 2005 IEEE.

no feedback

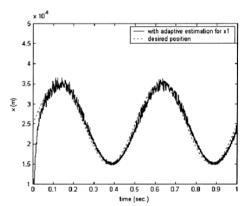


Figure 11 on p. 144 in: Piyabongkarn, D., Y. Sun, R. Rajamani, A. Sezen, and B. J. Nelson. "Travel Range Extension of a MEMS Electrostatic Microactuator." *IEEE Transactions on Control Systems Technology* 13, no. 1 (January 2005): 138-145. © 2005 IEEE.

with feedback

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Stabilization of unstable systems

> However:

- All potentially unstable modes must be both observable and controllable
- Observable means that the sensor provides state information about the mode
- Controllable means that the control inputs can modify the mode
- If a mode has both attributes, it can be stabilized (at least in theory) with feedback
- > Adding sensors to a system improves observability of modes
- > Adding actuators improves controllability
- > This can be generalized from unstable to unwanted...

Control for MEMS

- > Electrostatic traps for cells
- The goal is to trap single cells at each site
- > System is currently run open loop
- Could we do better if we ran closedloop?
- Need to sense: optical or electrical
- Need to actuate
 - This is hard...

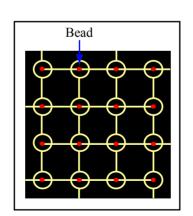
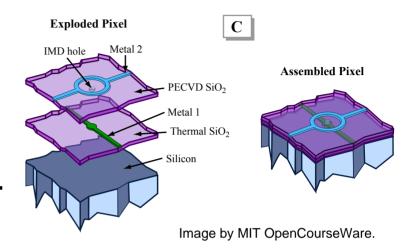


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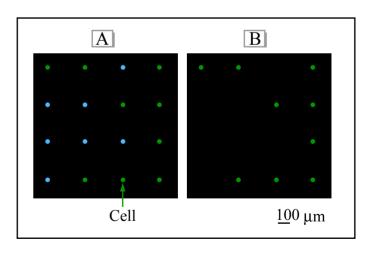


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Control for MEMS

- Many MEMS devices/systems are run open loop why?
- > Open loop
 - Does not need additional sensors or actuators
 - » These increase fab complexity, chip size, cost, etc.
 - But is sensitive to perturbations
- > Closed loop
 - Requires extra complexity
 - More stable performance
- > If you don't need closed-loop control, don't use it

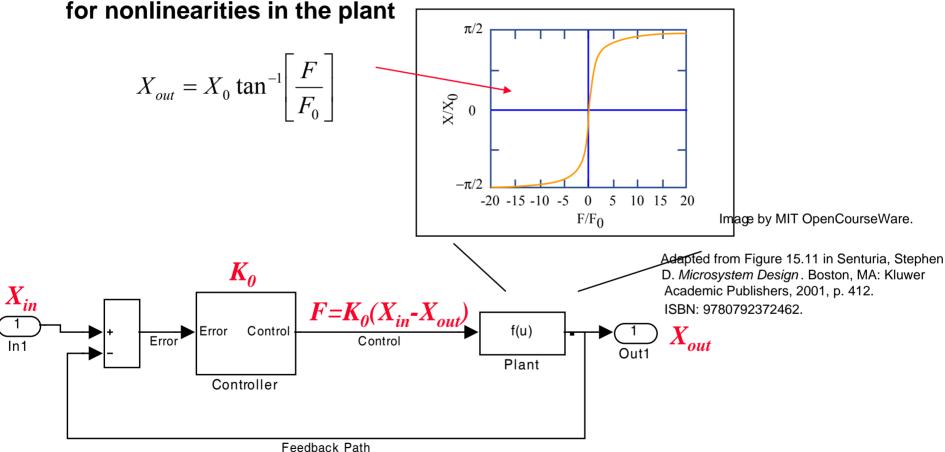
Outline

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- > The uses of (linear) feedback
- > Feedback of Nonlinear Systems
 - Quasi-static systems
 - Oscillators

Feedback in Nonlinear Systems

- Can no longer use nice algebraic forms
- > However, the same idea still holds:

• The controller pre-distorts the control signal so as to compensate



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Feedback in Nonlinear Systems

- > Controller "linearizes" in nonlinear system
- > This also occurs in op-amps

$$X_{out} = X_0 \tan^{-1} \left[\frac{K_0 \left(X_{in} - X_{out} \right)}{F_0} \right]$$



$$X_{in} - X_{out} = \frac{F_0}{K_0} \tan \left[\frac{X_{out}}{X_0} \right]$$
$$X_{in} - X_{out} \approx 0 \text{ for } K_0 >> F_0$$

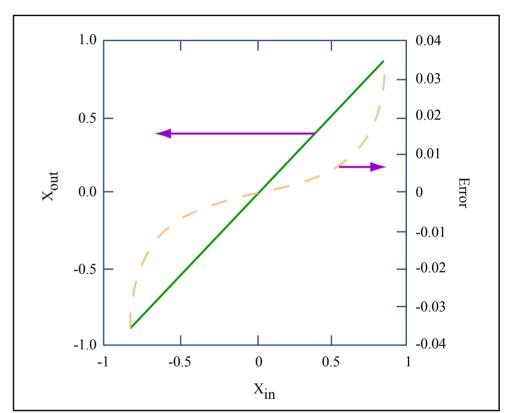


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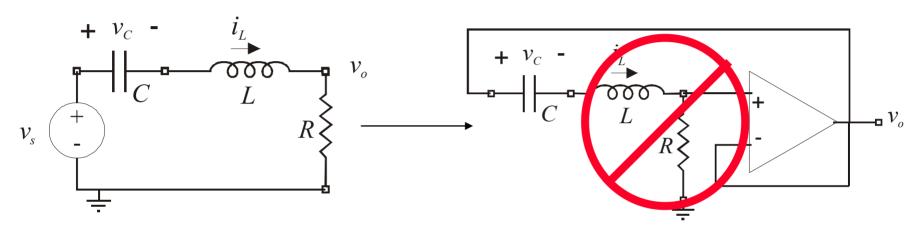
Adapted from Figure 15.12 in: Senturia, Stephen D. *Microsystem Design*. Boston, MA: Kluwer Academic Publishers, 2001, p. 413. ISBN: 9780792372462.

Resonators, Oscillators and Limit Cycles

- > Resonator: a passive element that exhibits underdamped oscillatory behavior
- Oscillator: a resonator plus an active gain element that compensates the resonator losses and results in steady oscillatory behavior
- Limiting: a required nonlinearity in either the resonator or gain element
- > Limit Cycle: stable closed path in state space

Example: Resonant RLC Circuit

> While a linear amplifier can *theoretically* produce an undamped linear system, it cannot create an oscillator



$$\frac{dv_C}{dt} = \frac{1}{C}i_L$$

$$\frac{di_L}{dt} = \frac{1}{L} \left(v_S - v_C - i_L R \right)$$

$$\frac{dv_C}{dt} = \frac{1}{C}i_L$$

$$\frac{di_L}{dt} = \frac{1}{L} \left(v_0 - v_C - v_0 \right) = -\frac{v_C}{L}$$

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Example: Resonant RLC Circuit

- > No stable limit cycle
- > Vary gain A of op-amp circuit

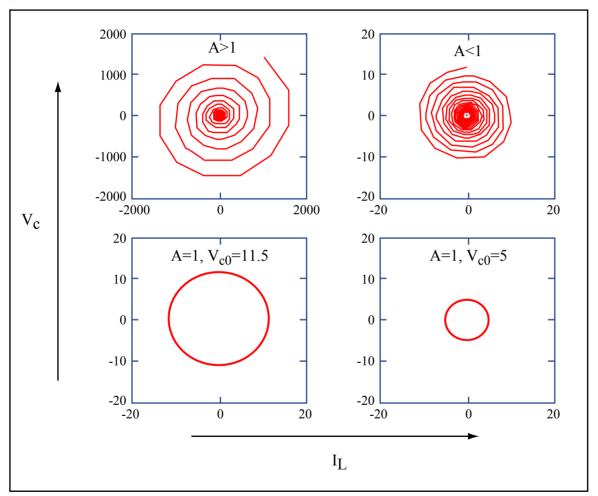


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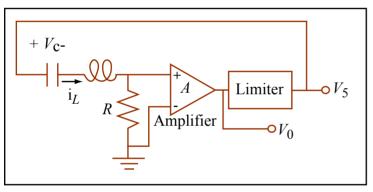
Adding a limiter creates an oscillator

> Add in arctangent limiter

state

$$\frac{dv_C}{dt} = \frac{1}{C}i_L$$

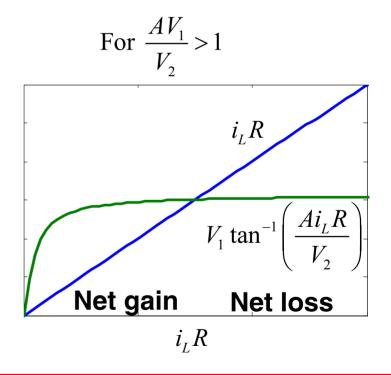
$$\frac{di_L}{dt} = \frac{1}{L} \left[V_1 \tan^{-1} \left(\frac{Ai_L R}{V_2} \right) - v_C - i_L R \right]$$



 $v_s = V_1 \tan^{-1} \left(\frac{v_0}{V_2} \right)$

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Adapted from Figure 15.15 in Senturia, Stephen D. Microsystem Design. Boston, MA: Kluwer Academic Publishers, 2001, p. 416. ISBN: 9780792372462.



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Marginal Oscillator

> Gradual limiting leads to nearly sinusoidal waveforms for weakly damped resonators

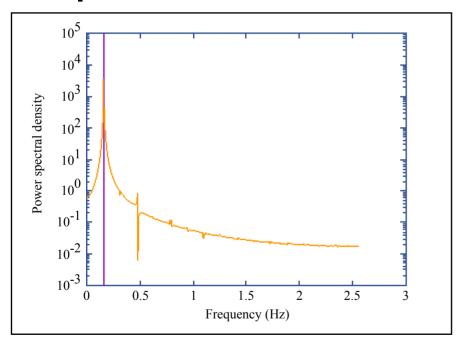
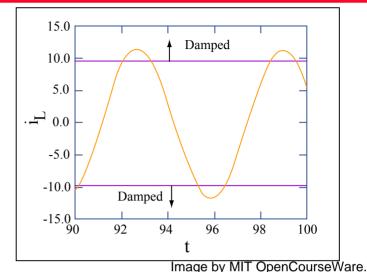
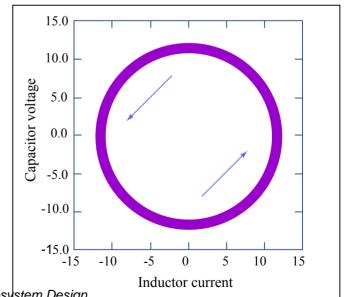


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JV: 2.372J/6.777J Spring 2007, Lecture 17 - 36

Oscillator Parting Comments

- > Do not confuse a resonator with an oscillator
- The oscillator is the combined result of a resonator with a suitably designed circuit
- > The oscillator is intrinsically nonlinear
- > The limit cycle obeys its own dynamics, which can be discovered by analyzing the perturbation of a limit cycle and the time required to recover

Conclusions

- > When properly designed, feedback can
 - Reduce sensitivity to variations
 - Decrease response time of system
 - Control output with zero DC error
 - Stabilize unstable systems
- > But it may be too complicated or unnecessary for your MEMS part → a systems issue
- > All elements in the feedback path have poles, and these can cause instabilities
- Numerous methods exist to analyze control systems in frequency, time, root-locus, and state-space domains